

Form PTO-1449 (Rev. 8-88)	Attorney Docket No. NWN02-002-DIV-US	Serial No. 10/671,381
<b>INFORMATION DISCLOSURE CITATION</b> (Use several sheets if necessary)	First Named Inventor: Chad Mirkin	
	Filing Date: September 25, 2003	Group: 1762

U.S. PATENT DOCUMENTS							
Examiner Initials*		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
WPF/	Z1	5,053,100	10/1991	Hayes et al.			
	Z2	5,514,501	05/1996	Tarlov			
	Z4	5,883,387	03/1999	Matsuyama et al.			
	Z5	5,922,214	07/1999	Liu et al.			
	Z7	6,156,215	12/2000	Shimada et al.			
	Z8	6,284,113	09/2001	Bjornson et al.			
	Z10	6,353,219	03/2002	Kley			
	Z11	6,409,900	06/2002	Parce et al.			
	Z12	6,429,025	08/2002	Parce et al.			
	Z13	6,444,111	09/2002	Montgomery			
	Z14	6,555,389	04/2003	Ullman et al.			
	Z15	6,635,311	10/2003	Mirkin et al.			
	Z16	6,642,129	11/2003	Liu et al.			
	Z17	6,827,979	12/2004	Mirkin et al.			
	Z18	6,867,443	03/2005	Liu et al.			
	Z19	6,943,417	09/2005	Boland et al.			
	Z20	7,034,854	04/2006	Cruchon-Dupeyrat et al.			
	Z21	7,042,828	05/2006	Kley			
	Z22	2001/0020588	09/2001	Adourian et al.			
	Z23	2001/0036674	11/2001	Indermuhle et al.			
	Z24	2002/0025279	02/2002	Weigl et al.			
	Z25	2002/0123153	09/2002	Moon et al.			
	Z26	2003/0017077	01/2003	Hahn et al.			
	Z27	2003/0026740	02/2003	Staats			
	Z29	2003/0082080	05/2003	Zimmermann et al.			
	Z31	2004/0018116	01/2004	Desmond et al.			
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	Z33	7,081,624	07/2006	Liu et al.			
	Z34	2005/0201257	09/2005	Champion et al.			

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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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Examiner Initials*		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
/WPF/	Z35	2005/0236586	10/2005	Liu			
↓	Z36	2004/0223886	11/2004	Liu et al.			
↓	Z38	2004/0228962	11/2004	Liu et al.			

FOREIGN PATENT DOCUMENTS								
Examiner Initials*		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
/WPF/	Y1	WO 00/41213	07/2000	WO				
↓	Y2	WO 01/91855 A1	12/2001	WO				
↓	Y3	EP 1388369 A2	02/2004	EP				
↓	Y4	EP 0786842 A1	07/1997	EP				
↓	Y6	WO 2004/105046 A2	12/2004	WO				

Examiner Initials*		OTHER ITEMS - NON PATENT LITERATURE DOCUMENTS	
		Include, as applicable: Author, Title, Date, Publisher, Edition or Volume, Pertinent Pages	
/WPF/	X1	Kim et al., "A novel AFM Chip for fountain pen nanolithography - design and microfabrication," Mat. Res. Soc. Symp. Proc., Vol. 782, pp. A5.56.1-A5.56.6, 2004.	
↓	X2	Xu et al., "Microfabricated quill-type surface patterning tools for the creation of biological micro/nano arrays," Biomedical Microdevices 6:2, pp. 117-123, 2004.	
↓	X3	Deladi et al., "Micromachined fountain pen for atomic force microscope-based nanopatterning," Applied Physics Letters, Vol. 85, No. 22, pp. 5361-5363, 2004.	
↓	X4	Lewis et al., "Fountain pen nanochemistry: atomic force control of chrome etching," Applied Physics Letters, Vol. 75, No. 17, pp. 2689-2691, 1999.	
↓	X5	Baldock et al., "Microfabricated Devices for Chemical and Biochemical Analysis Systems," located at <a href="http://www.in.umist.ac.uk/">http://www.in.umist.ac.uk/</a> , presented at Microsystems 2010, Daresbury, Cheshire, 1 page, 2000.	
↓	X13	Bullen et al., "Design, Fabrication, and Characterization of Thermally Actuated Probe Arrays for Dip Pen Nanolithography," J. Microelectromechanical Systems, vol. 13, no. 4, pp. 594-602, August 2004.	
↓	X15	Higa et al., "Fabrication of Microcantilever with a Silicon Tip Prepared by Anodization", Japanese Journal of Applied Physics, Vol. 37, Part 1, No. 12B, pp.7078-7080, 1998.	

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/WPF/	X16	Hong et al., "A nanoplotter with both parallel and serial writing capabilities," Science, Vol. 288, pp. 1808-1811, 2000.
	X17	International Search Report and Written Opinion for PCT Application No. PCT/US04/13974, 9 pages, dated November 30, 2005.
	X18	International Search Report for PCT Application No. PCT/US2004/015161, 7 pages, dated February 10, 2005.
	X21	Wang et al., "Multifunctional probe array for nano patterning and imaging," Nano Letters, vol. 5, no. 10, pp 1867-1872, 2005.
	X33	International Search Report and Written Opinion for PCT Application No. PCT/US20006/035826, 13 pages, dated December 19, 2006.
	X38	Van Zant, "Microchip Fabrication: A Practical Guide to Semiconductor Processing," Chapter 16 Semiconductor Devices and Integrated Circuit Formation, pp. 491-529, 2000.
	X43	Wang et al., "Scanning probe lithography tips with spring-on tip designs: Analysis, fabrication, and testing", Applied Physics Letters, 87, 054102-1 to 054102-3, 2005.
	X47	Zou et al., "A mould-and-transfer technology for fabricating scanning probe microscopy probes," Journal of Micromechanics and Microengineering, Vol. 14, pp. 204-211, 2004.
	X48	Wang et al., "Thermally actuated probe array for parallel dip-pen nanolithography," J. Vac. Sci. Technol. B., 22(6) , pp. 2563-2567, 2004
	X49	Zhang et al., "Passive and Active Probe Arrays for Dip-Pen Nanolithography," First IEEE Conference on Nanotechnology, Maui, HI, 5 pages, 2001.
↓	X50	Hong et al., "Multiple Ink Nanolithography: Toward a Multiple-Pen Nano-Plotter", Science, Vol. 286, pp. 523-525, 1999.

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